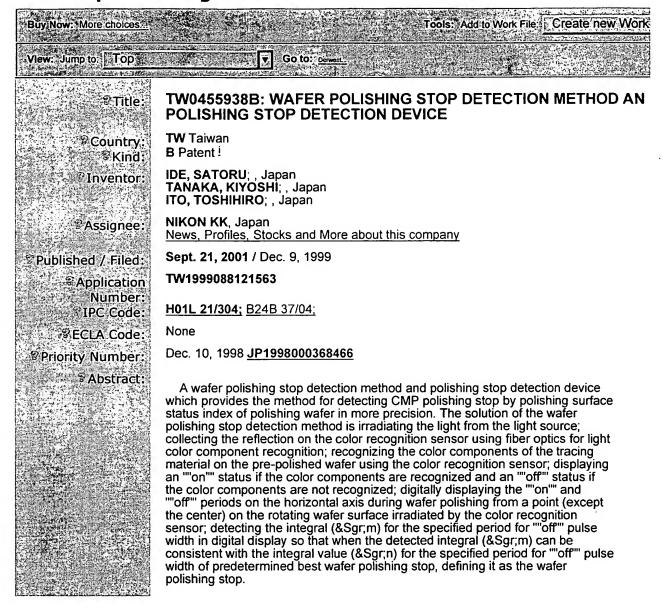


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Buy PDF	<u>Publication</u>	Pub. Date	Filed	Title
	US6342166B1	Jan. 29, 2002		
2	US6342166	Jan. 29, 2002	Dec. 6, 1999	Method of detecting end point of p wafer and apparatus for detecting polishing
	TW0455938B	Sept. 21, 2001		WAFER POLISHING STOP DETE METHOD AND POLISHING STOP DEVICE
	KR0048040A		500, 0, 1000	METHOD FOR DETECTING POLI POINT OF WAFER AND APPARA DETECTING THE POLISHING EN
	JP2000183002A2	June 30, 2000	Dec. 10, 1998	METHOD AND DEVICE FOR DET WAFER POLISH END-POINT

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